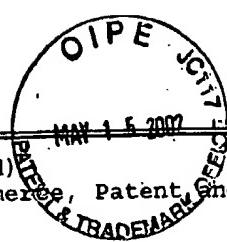


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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Docket No. CIB-1632A	Serial No. 09/918,395
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Applicant Ronald P. Reade et al.

Filing Date July 30, 2001	Group Unknown
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>PR</i>	AA	6,060,375	5/9/00	Owyang et al.	438	585	7/31/96
<i>PR</i>	AB	5,872,080	2/16/99	Arendt et al.	505	238	4/19/95
<i>PR</i>	AC	5,650,378	7/22/97	Iijima et al.	505	473	8/3/95
<i>PR</i>	AD	5,432,151	7/11/95	Russo et al.	505	474	7/12/93
<i>PR</i>	AE	5,262,394	11/16/93	Wu et al.	505	1	12/27/91
	AF						
	AG						
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	AK						

Foreign Patent Documents

Translation

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<i>PR</i>	AL	01/08169	07/2000	WIPO	—	—		
<i>PR</i>	AM	01/08170	07/2000	WIPO	—	—		
<i>PR</i>	AN	01/08231	07/2000	WIPO	—	—		
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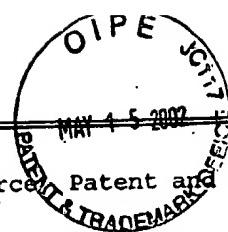
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<i>PR</i>	AR	Berdahl, P., et al., "Angular Magnetoresistance Provides Texture Information on High-T _c Conductors", <u>Physica C</u> , 195, 1992, pp. 93-102.
<i>PR</i>	AS	Bradley, Mark R., et al., "Theory of Thin-Film Orientation by Ion Bombardment during Deposition", <u>J. Appl. Phys.</u> 60 (12), 15 December 1986, pp. 4160-4164.
<i>PR</i>	AT	Dimos, D., et al., "Superconducting Transport Properties of Grain Boundaries in YBa ₂ Cu ₃ O _x Bicrystals", <u>Physical Review B</u> , Vol. 41, No. 7, March 1, 1990, pp. 4038-4049.

Examiner *Yong Wang* Date Considered *7/30/03*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT
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Docket No. CIB-1632A Serial No. 09/918,395

Applicant Ronald P. Reade et al.

Filing Date July 30, 2001 Group Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
BA							
BB							
BC							
BD							
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Foreign Patent Documents

Translation

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<i>pm</i>	BM	99/16941	09/1998	WIPO	—	—		
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<i>pm</i>	BO	01/26165	07/2000	WIPO	—	—	JUN 1 2002	CEIV
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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

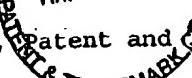
<i>pm</i>	BR	Dobrev, D., "Ion-Beam-Induced Texture Formation in Vacuum-Condensed Thin Metal Films", <u>Thin Solid Films</u> 92, 1982, pp. 41-53.
<i>pm</i>	BS	Fork, D.K., et al., "High Critical Currents in Strained Epitaxial YBa ₂ Cu ₃ O _{7-x} on Si", <u>Appl. Phys. Lett.</u> 57 (11), 10 September 1990, pp. 1161-1163.
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Examiner *Roslyn Reade* Date Considered 7/30/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not consider d. Include copy of this form with your communication to applicant.

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Docket No.

CIB-1632A

Serial No.

09/918,395

Applicant

Ronald P. Reade et al.

Filing Date

July 30, 2001

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Unknown

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
CA							
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<i>mr</i>	CP	01/11428	07/2000	WIPO	—	—		

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<i>mr</i>	CR	Iijima, Y., et al., "Biaxially Aligned YSZ Buffer Layer on Polycrystalline Substrates", paper prepared for Proceedings of the Fourth International Symposium on Superconductivity, Tokyo, Japan, October 14-17, 1991, pp. 1-4.
<i>mr</i>	CS	Iijima, Y., et al., "In-Plane Aligned $\text{YBa}_2\text{Cu}_3\text{O}_{6-x}$ Thin Films Deposited on Polycrystalline Metallic Substrates", <i>Appl. Phys. Lett.</i> 60 (6), 10 February 1992, pp. 769-771.
<i>mr</i>	CT	Jia, Q.X., et al., "Sputter Deposition of $\text{YBa}_2\text{Cu}_3\text{O}_{6-x}$ Films on Si at 500°C with Conducting Metallic Oxide as a Buffer Layer" <i>Appl. Phys. Lett.</i> 57 (3), 16 July 1990, pp. 304-306.

Examiner *Ronald P. Reade*Date Considered *7/30/03*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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Serial No.

09/918,395

Applicant

Ronald P. Reade et al.

Filing Date

July 30, 2001

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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		Document Number	Date	Country	Class	Subclass	Yes	No
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	DN							
	DO							
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<i>mr</i>	DR	Kumar, Ashok, et al., "Synthesis of Superconducting YBa ₂ Cu ₃ O ₇ , Thin Films on Nickel-Based Superalloy Using In Situ Pulsed Laser Deposition", <u>Appl. Phys. Lett.</u> 57 (24), 10 December 1990, pp. 2594-2596.
<i>mr</i>	DS	Lioucas, Ch.B., et al., "Phase Transformation of Hydrogen Free Amorphous Carbon Films under Ion Beam Bombardment", <u>Carbon</u> , Vol. 36, No. 5-6, 1998, pp. 545-548.
<i>mr</i>	DT	Mizutani, T., "Compositional and Structural Modifications of Amorphous SiO ₂ by Low-Energy Ion and Neutral Beam Irradiation", <u>Journal of Non-Crystalline Solids</u> 181, 1995, pp. 123-134.

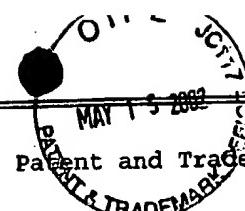
Examiner *Ronald P. Reade*

Date Considered

7/30/03

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Docket No.

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Serial No.

09/918,395

Applicant

Ronald P. Reade et al.

Filing Date

July 30, 2001

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U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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Foreign Patent Documents

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		Document Number	Date	Country	Class	Subclass	Yes	No
EL								
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<i>Mr</i>	ER	Narumi, E., et al., "Critical Current Density Enhancement in $\text{YBa}_2\text{Cu}_3\text{O}_{6.6}$ Films on Buffered Metallic Substrates", <u>Appl. Phys. Lett.</u> 58 (11), 18 March 1991, pp. 1202-1204.
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<i>Mr</i>	ET	Pangal, K. et al., "Integration of Amorphous and Polycrystalline Silicon Thin-Film Transistors Through Selective Crystallization of Amorphous Silicon", <u>Appl. Phys. Lett.</u> 75 (14), 4 October 1999, pp. 2091-2093.

Examiner *Ronald P. Reade* Date Considered *7/30/02*

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		Applicant Ronald P. Reade et al.	
		July 30, 2001	Group Unknown

U.S. Patent Documents

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Foreign Patent Documents

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<i>Mr.</i>	FR	Reade, R.P., et al., "Characterization of Y-Ba-Cu-O Thin Films and Yttria-Stabilized Zirconia Intermediate Layers on Metal Alloys Grown by Pulsed Laser Deposition", <i>Appl. Phys. Lett.</i> 59 (6), 5 August 1991, pp. 739-741.
<i>Mr.</i>	FS	Reade, R.P., et al., "Laser Deposition of Biaxially Textured Yttria-Stabilized Zirconia Buffer Layers on Polycrystalline Metallic Alloys for High Critical Current Y-Ba-Cu-O Thin Films", <i>Appl. Phys. Lett.</i> 61 (18), 2 November 1992, pp. 2231-2233.
<i>Mr.</i>	FT	Russo, R.E., et al., "Fabrication and Characterization of Y-Ba-Cu-O Thin Films on Stainless-Steel Substrates", submitted by authors for publication in <u>High Temperature Superconducting Compounds II</u> , edited by S.H. Whang (Minerals, Metals, and Materials Society, Warrendale), 1990, pp. 1-6.

Examiner *Reade, P. et al.* Date Considered *7/30/03*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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Docket No.

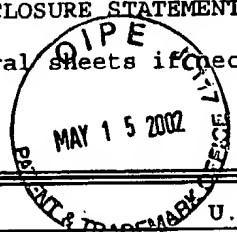
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CIB-1632A

09/918,395

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Applicant

Ronald P. Reade et al.

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U.S. Patent Documents

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	AL						1	
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	AN						1	
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<i>Mur</i>	AR	Russo, R.E., et al., "Metal Buffer Layers and Y-Ba-Cu-O Thin-Films on Pt and Stainless-Steel Using Pulsed Laser Deposition", <u>J. Appl. Phys.</u> 68 (3), 1 August 1990, pp. 1354-1356.
<i>Mur</i>	AS	Tiwari, P., et al., "In Situ Single Chamber Laser Processing of YBa ₂ Cu ₃ O _{7-x} Superconducting Thin Films on Si (100) with Yttria-Stabilized Zirconia Buffer Layers", <u>Appl. Phys. Lett.</u> 57 (15), 8 October 1990, pp. 1578-1580.
<i>Mur</i>	AT	Van Wyk, G.N., "The Dependence of Ion Bombardment Induced Preferential Orientation on the Direction of the Ion Beam", <u>Radiation Effects Letters</u> , Vol. 57, 1980, pp. 45-50.

Examiner

Ronald P. Reade

Date Considered

7/30/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		Applicant Ronald P. Reade et al.	
		Filing Date July 30, 2001	Group Unknown

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AN						RECEIVED	
AO						RECEIVED	
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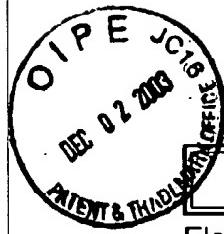
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<i>Mr</i>	AR	Van Wyk, G.N., et al., "Ion Bombardment Induced Preferential Orientation in Polycrystalline Cu Targets", <u>Radiation Effects</u> , Vol. 38, 1978, pp. 245-247.
<i>Mr</i>	AS	Wang, C.P. et al., "Deposition of In-Plane Textured MgO on Amorphous Si ₃ N ₄ Substrates by Ion-Beam-Assisted Deposition and Comparisons with Ion-Beam-Assisted Deposited Yttria-Stabilized-Zirconia", <u>Appl. Phys. Lett.</u> 71 (20), 17 November 1997, pp. 2955-2957.
<i>Mr</i>	AT	Wiesmann, J., et al., "Large-Area Deposition of Biaxially Textured YSZ Buffer Layers Using an IBAD-Process", <u>Nucl. Instr. and Meth. in Phys. Res. B</u> 120, 1996, pp. 290-292.

Examiner: *Ronald P. Reade* Date Considered

7/30/03

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Title of Invention	ION TEXTURING METHODS AND ARTICLES
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Application Number: 09/918395
 Confirmation Number: 9970
 First Named Applicant: RONALD READE
 Attorney Docket Number: IB-1632A
 Art Unit: 1753
 Examiner: RODNEY GLENN MCDONALD
 Search string: (6258472 or 6190752 or 6498549 or 6537689
 or 5246741 or 4776925 or 5607781 or 5601654
 or 6033471 or 5372089 or 20020017235 or
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US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6258472	2001-07-10	Neumuller et al.	B1	478	701
	2	6190752	2001-02-20	Do et al.	B1	478	141
	3	6498549	2002-12-24	Jiang et al.	B1	333	202
	4	6537689	2003-03-25	Schoop et al.	B2	478	701
	5	5246741	2003-09-21	Ouhata et al.	B1	477	524
	6	4776925	1988-10-11	Fossum et al.	B1	478	297
	7	5607781	1997-03-04	Okuno et al.	B1	110	7234C
	8	5601654	1997-02-11	Springer	B1	478	694ML
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1	20020017235	2002-02-14	Nagasaki et al.	A1	117 106
2	20020041973	2002-04-11	Belouet	A1	428 623
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Signature

Examiner Name	Date
<i>Hodgson, Donald</i>	9/12/04



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Application Number	09/918,395
Filing Date	07/30/2001
First Named Inventor	Ronald P. Reade
Art Unit	1753
Examiner Name	Rodney G. McDonald

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FOREIGN PATENT DOCUMENTS

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Padron Mr. Gualdi

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